APPENDIX

Please amend claim 1 as follows:

1 (Amended). A method comprising:

forming a buried line of a first [conductive] <u>conductivity</u> type in a <u>bulk</u> substrate, said buried line including a pair of more lightly doped regions [around] <u>above and below</u> a more heavily doped region;

creating a region of a second conductivity type opposite said first conductivity type [over said line] in said bulk substrate; and

forming a phase-change material over said region.

Please amend claim 11 as follows:

- 11 (Amended). A memory cell comprising:
 - a bulk substrate;
 - a phase-change material over said substrate;
- a buried line of a first conductivity type <u>formed</u> in said substrate, said buried line including a [pair of] more lightly doped [regions around] <u>region over</u> a more heavily doped region and a more lightly doped region under said more heavily doped region; and
- a region of a second conductivity type opposite said first conductivity type over said line and under said phase-change material.

Please amend claim 21 as follows:

21 (Amended). An electronic device comprising:

a system memory circuit including:

a [surface] bulk substrate;

a phase-change material over said [surface] substrate; [and]

a conductive line of a first conductivity type in said [surface having]

substrate, said line including a more heavily doped region sandwiched between more lightly doped regions, said conductive line providing signals to said phase-change material; and

a region of a second conductivity type between said phase-change material

and said conductive line; and

a processor coupled to said system memory circuit.